IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : H. OHTANI Art Unit: Serial No.: 08/730,038 Examiner:

Filed : 5/23/97

Title : SEMICONDUCTOR INTEGRATED CIRCUIT AND FABRICATING METHOD

THEREOF

Assistant Commissioner for Patents Washington, DC 20231

TRANSMITTAL OF PRIORITY DOCUMENT(S) UNDER 35 U.S.C. 119

Applicant hereby confirms his claim of priority under 35 U.S.C. 119 from Japanese Application No. 8-165272 filed June 4, 1996. A certified copy of the application from which priority is claimed is submitted herewith.

Please charge any fees due in this respect to Deposit Account No. 06-1050.

Respectfully submitted,

Req. No. 32,030

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36106.LJ1

M-16-97 Date of Deposit

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated above and is addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231.

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This is to certify that the annexed is a true copy of the following application as filed this Office.

→ 願 年 月 日 te of Application:

1996年 6月 4日

願番号 Splication Number:

平成 8年特許顯第165272号

願 人 licant (s):

in the same

株式会社半導体エネルギー研究所

1997年 5月16日

特許庁長官 Commissioner, Patent Office 荒井 寿 漫 區